

EAST Search History

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L1	2889	(702/57,58,109,110,117,118,119).CCLS.	US- PGPUB; USPAT; USOCR	OR	OFF	2008/07/04 15:57
L2	438	(324/718,716).CCLS.	US- PGPUB; USPAT; USOCR	OR	OFF	2008/07/04 15:57
L4	750	(438/18).CCLS.	US- PGPUB; USPAT; USOCR	OR	OFF	2008/07/04 15:57
L5	946	(700/109,110).CCLS.	US- PGPUB; USPAT; USOCR	OR	OFF	2008/07/04 15:58
L6	18	(calculate\$3 manipulate\$3) with (semiconductor\$1 wafer\$1 structure\$1 wafer\$1) with (goodness with fit\$3)	US- PGPUB; USPAT; USOCR	OR	ON	2008/07/04 15:58
L7	7540	(wafer\$1 chuck\$1 workpiece\$1) with (detect\$3 monitor\$3) with (defect\$3 anomaly\$3 error\$1 fault\$3 fail\$3)	US- PGPUB; USPAT; USOCR	OR	ON	2008/07/04 15:59

L8	163	test\$3 with condition\$3 with (temperatur\$3 with intensity)	US- PGPUB; USPAT; USOCR	OR	ON	2008/07/04 15:59
L9	0	(curve near fltt\$3) and (process\$3 with (control \$3 monitor\$3)) and (detect\$3 with defect\$1) and ((goodness nearl (fit\$4 measur\$3)) (coefficient\$1 near correlation\$1)) and (sheet\$1 near (resistance resistivity))	US- PGPUB; USPAT; USOCR	OR	ON	2008/07/04 16:00
L10	0	((wafer\$1 near defect\$1)with (screen\$3 monitor \$3)) and (statistic\$3 with process\$3 with control \$3) and (ATE with testers)	US- PGPUB; USPAT; USOCR	OR	ON	2008/07/04 16:01
L11	0	(wafer\$1 with tester\$1) same (process\$3 with evaluat\$3) same (statistic\$3 with (fit\$3 best\$1 flt \$3))	US- PGPUB; USPAT; USOCR	OR	ON	2008/07/04 16:01
L12	7	("4031370" "4905170").PN. OR ("5796983").URPN.	US- PGPUB; USPAT; USOCR	OR	ON	2008/07/04 16:01
L13	2	(1 2 4 5) and 6	US- PGPUB; USPAT; USOCR	OR	ON	2008/07/04 16:02
L14	18	("4855253" "5717490" "5739909" "5835225" "6015718" "6072191" "6146910" "6263255" "6297880" "6298470" "6309900" "6347291" "6484064").PN. OR ("6743646").URPN.	US- PGPUB; USPAT; USOCR	OR	ON	2008/07/04 16:02

L15	8	((wafer\$1 with tester\$1) same (process\$3 with evaluat\$3) same screen\$3 and (control\$3 with process\$3))	US- PGPUB; USPAT; USOCR	OR	ON	2008/07/04 16:02
L16	48	((curve near fitt\$3) and (process\$3 with (control \$3 monitor\$3)) and (detect\$3 with defect\$1) and ((goodness nearl (fit\$4 measur\$3)) ((coefficient\$1 near correlation\$1)) and (sheet\$1 near (resistance resistivity)))	US- PGPUB; USPAT; USOCR	OR	ON	2008/07/04 16:03
L17	0	((wafer\$1 with tester\$1) same (process\$3 with evaluat\$3) same (statistic\$3 with (fit\$3 GOF best\$1fit\$3))	US- PGPUB; USPAT; USOCR	OR	ON	2008/07/04 16:04
L18	0	((manipulat\$5 calculat\$5 form\$3) with ((goodness near1 (fit\$3 measur\$4 statistical \$3))) and ((semiconductor\$1 wafer\$1) with (form \$3 near process\$3)) and (independent with variable\$1))	US- PGPUB; USPAT; USOCR	OR	ON	2008/07/04 16:04
L19	19	(test\$3 with structur\$3) and (wafer\$1 chuck\$1 with workpiece\$1) and (defect\$3 with monitor \$3) and ((goodness with fit\$3) (curve\$1 with fit \$3))	US- PGPUB; USPAT; USOCR	OR	ON	2008/07/04 16:05
L20	1	(structure with test\$3 with parameter\$1) and ((measur\$3 with monitor\$3) with value\$1) and ((goodness with fit\$3 with differenc\$3) and (value \$1 with differenc\$3))	US- PGPUB; USPAT; USOCR	OR	ON	2008/07/04 16:06
L21	5	((histor\$3 with value\$1) same curve\$1) and ((goodness with fit\$3) and ((control\$3 with limit \$3) (threshold with value\$1) (referenc\$3 with value\$1)))	US- PGPUB; USPAT; USOCR	OR	ON	2008/07/04 16:06

L22	0	(12 4 5) and 20	US- PGPUB; USPAT; USOCR	OR	ON	2008/07/04 16:07
L23	7	(12 4 5) and 12	US- PGPUB; USPAT; USOCR	OR	ON	2008/07/04 16:07
L24	0	23 and 14	US- PGPUB; USPAT; USOCR	OR	ON	2008/07/04 16:07
L25	0	23 and 8	US- PGPUB; USPAT; USOCR	OR	ON	2008/07/04 16:07
L26	2	(fit\$3 with curve\$1 with value\$1) and ((wafer\$1 chuck\$1 workpiece\$1 substrat\$3 structure\$1) with monitor\$3 with defect\$3)	US- PGPUB; USPAT; USOCR	OR	ON	2008/07/04 16:08
L27	0	(fit\$3 with curve\$1 with value\$1) and ((wafer\$1 chuck\$1 workpiece\$1 substrat\$3 structure\$1) with monitor\$3 with defect\$3) and (compar\$3 with ((referenc\$3 threshold) with value\$1))	US- PGPUB; USPAT; USOCR	OR	ON	2008/07/04 16:08
L28	204	(wafer\$1 chuck\$1 workpiece\$1) with (detec\$3 monitor\$3) with (defect\$3 anomal\$3 error\$1 fault\$3 fail\$3) and (fit\$3 with (curv\$3 graph\$3 plot\$3))	US- PGPUB; USPAT; USOCR	OR	ON	2008/07/04 16:08

L29	2	("5345392" "6968291").PN. OR ("7081823").URPN.	US- PGPUB; USPAT; USOCR	OR	ON	2008/07/04 16:09
L30	30	("4933887" "4944590" "4950990" "4965451" "5020920" "5047713" "5099441").PN. OR ("5667300").URPN.	US- PGPUB; USPAT; USOCR	OR	ON	2008/07/04 16:09
L32	0	((manipulat\$5 calculat\$5 form\$3) with (goodness near1 (fitS3 measur\$4 statistical \$3))) and ((semiconductor\$1 wafer\$1) with (form\$3 near process\$3)) and (independent with variable\$1)).clm.	US- PGPUB; USPAT; USOCR	OR	ON	2008/07/04 16:11
L33	0	32 and (1 2 4 5)	US- PGPUB; USPAT; USOCR	OR	ON	2008/07/04 16:11
L34	1	(monitor\$3 with (process\$3 near stability)) and (fit\$3 with value\$1) and (linear\$3 with regression\$3) and (coefficient\$1 near (relat\$3 correlat\$3))	US- PGPUB; USPAT; USOCR	OR	ON	2008/07/04 16:11
L35	1	(monitor\$3 with (process\$3 near stability)) and (fit\$3 with value\$1) and (linear\$3 with regression\$3) and (coefficient\$1 near (relat\$3 correlat\$3)) and (resist\$3 with measur\$3) and (effect\$3 with (length\$1 width))	US- PGPUB; USPAT; USOCR	OR	ON	2008/07/04 16:12
L36	1	(monitor\$3 with (process\$3 near stability)) and (fit\$3 with value\$1) and (linear\$3 with regression\$3) and (coefficient\$1 near (relat\$3 correlat\$3)) and (resist\$3 with measur\$3) and ((effect\$3 with (length\$1 width)) same wafer\$1)	US- PGPUB; USPAT; USOCR	OR	ON	2008/07/04 16:12

L37	0	((monitor\$3 with (process\$3 near stability)) and ((fit\$3 with value\$1) and ((linear\$3 with regression\$3) and (coefficient\$1 near (relat\$3 correlat\$3)) and (resist\$3 with measur\$3) and ((effect\$3 with (length\$1 width)) same wafer \$1))).clm.	US- PGPUB; USPAT; USOCR	OR	ON	2008/07/04 16:13
L38	0	(1 2 4 5) and 36	US- PGPUB; USPAT; USOCR	OR	ON	2008/07/04 16:13
L39	0	(1 2 4 5) and 37	US- PGPUB; USPAT; USOCR	OR	ON	2008/07/04 16:13

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